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Hayes
PATENT

Attorney Docket No. 046124-5055

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Takuya HOMME et al.)
Application No.: 09/737,818) Group Art Unit: 2878
Filed: December 18, 2000) Examiner: Timothy J. Moran
For: ORGANIC FILM VAPOR DEPOSITION) Confirmation No.: 2027
METHOD AND A SCINTILLATOR PANEL)

Commissioner for Patents
U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

AMENDMENT

In response to the Office Action dated February 18, 2003, the period for response being extended through June 18, 2003, by an accompanying petition for one month extension of time, please amend the above-identified application as follows:

IN THE CLAIMS

Please amend the claim 1 as follows:

1. (Once Amended) An organic film vapor deposition method comprising:
- B1 a first step of supporting a substrate formed with a scintillator on at least three protrusions of a target-support element disposed on a rotatable vapor deposition table so as to maintain a distance from said vapor deposition table;
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- second step of introducing said rotatable vapor deposition table having said substrate supported by said target-support element into a vapor deposition chamber of a CVD apparatus;
- and

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